



Docket Number (Optional) <b>DE920020040US1</b>	Application Number <b>10/707,288</b>
Applicant(s) <b>RAINER K. KRAUSE, ET AL.</b>	
Filing Date <b>12/03/03</b>	Group Art Unit <b>1752</b>

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

<b>ACW</b>		<b>SPIE Micromachining &amp; Microfabrication Symposium '96, "Imaging and Resist Technologies for the Micromachining Industry", David Craven, PP. 1-20</b>

EXAMINER <b>Amanda C. Wance</b>	DATE CONSIDERED <b>September 22, 2005</b>
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.